



# Assembly and operation of bent silicon pixel sensors towards the ALICE ITS3

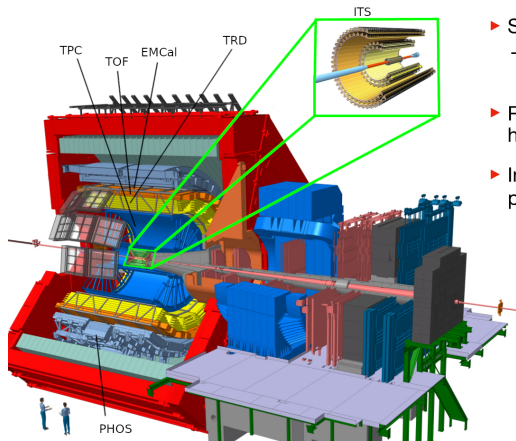
Alperen YÜNCÜ

May 8, 2024

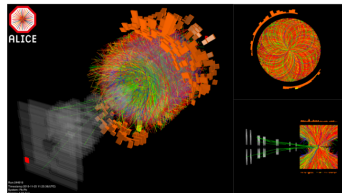


**FSP ALICE**  
Erforschung von  
Universum und Materie

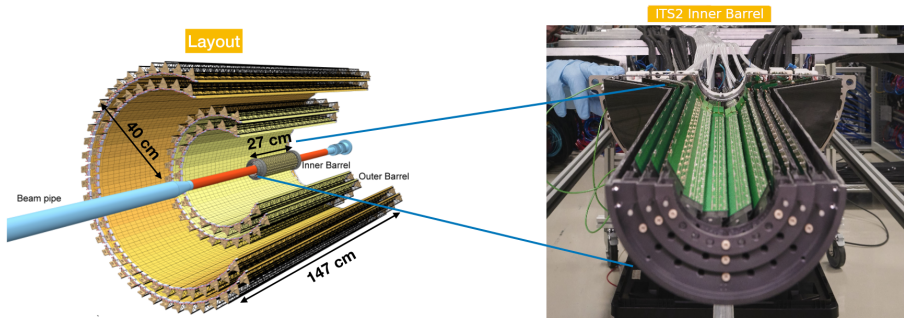
## Detector and main goals



- ▶ Study of QGP in heavy-ion collisions at LHC  
- i.e. up to  $O(10k)$  particles to be tracked in a single event
- ▶ Reconstruction of charm and beauty hadrons
- ▶ Interest in low momentum ( $\leq 1$  GeV/c) particle reconstruction

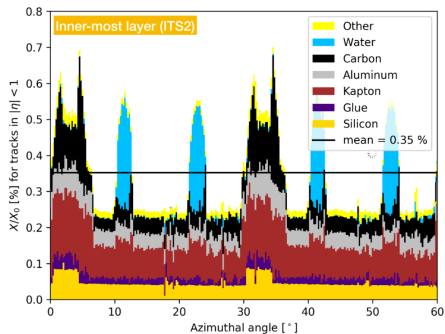


# Current Inner Tracking System (ITS2)



- ITS2 is expected to perform according to specifications or even better
- The inner barrel is ultra-light ( $0.35\% X_0$  per layer) but still most of the material comes from supports  $\implies$  **further improvements seem possible**
- Key questions:
  - ▶ Can we get closer to the interaction point?
  - ▶ Can we reduce the material budget even further?

# Motivation for ITS3

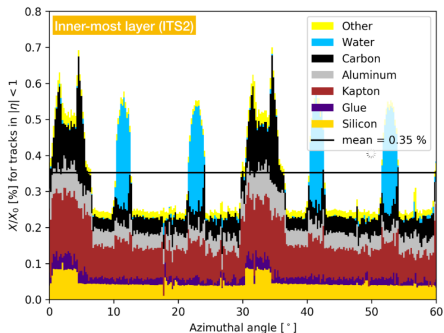


- Observations:

- ▶ 0.35 %  $X_0$  per layer
- ▶ Si makes only 1/7th of total material
- ▶ Irregularities due to support/cooling

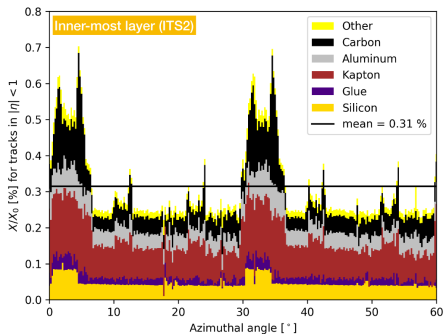


# Motivation for ITS3



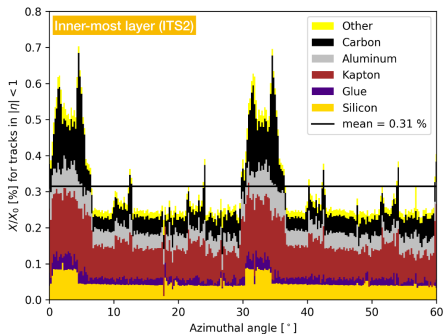
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- Removal of water cooling
  - ▶ Possible if power consumption stays below  $20 \text{ mW/cm}^2$
  - ▶ Air cooling

# Motivation for ITS3



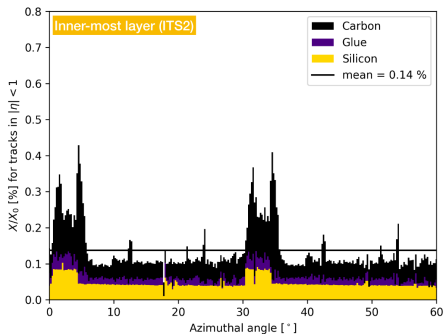
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  - ▶ 0.31 %  $X_0$  per layer

# Motivation for ITS3



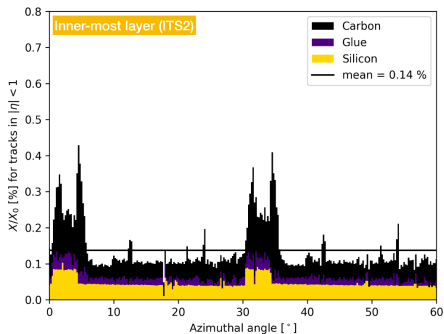
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- Removal of the circuit boards (power+data)
  - ▶ Possible if integrated on chip

# Motivation for ITS3



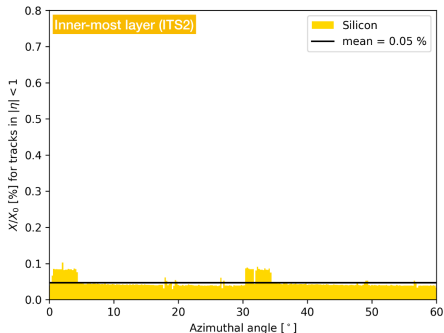
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  - ▶ Irregularities due to support/cooling
- Removal of water cooling
  - ▶ Possible if power consumption stays below 20 mW/cm<sup>2</sup>
  - ▶ Air cooling
  - ▶ 0.31 %  $X_0$  per layer
- Removal of the circuit boards (power+data)
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  - ▶ 0.14 %  $X_0$  per layer

# Motivation for ITS3



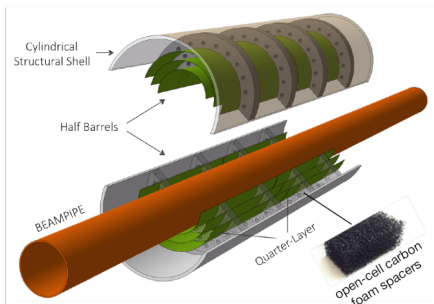
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  - ▶ Possible if power consumption stays below 20 mW/cm<sup>2</sup>
  - ▶ Air cooling
  - ▶ 0.31 %  $X_0$  per layer
- Removal of the circuit boards (power+data)
  - ▶ Possible if integrated on chip
  - ▶ 0.14 %  $X_0$  per layer
- Removal of mechanical support
  - ▶ Benefit from increased stiffness by bending Si wafers into cylindrical shape

# Motivation for ITS3



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- Removal of water cooling
  - ▶ Possible if power consumption stays below  $20 \text{ mW/cm}^2$
  - ▶ Air cooling
  - ▶ 0.31 %  $X_0$  per layer
- Removal of the circuit boards (power+data)
  - ▶ Possible if integrated on chip
  - ▶ 0.14 %  $X_0$  per layer
- Removal of mechanical support
  - ▶ Benefit from increased stiffness by bending Si wafers into cylindrical shape
  - ▶ 0.05 %  $X_0$  per layer

# ITS3 detector concept

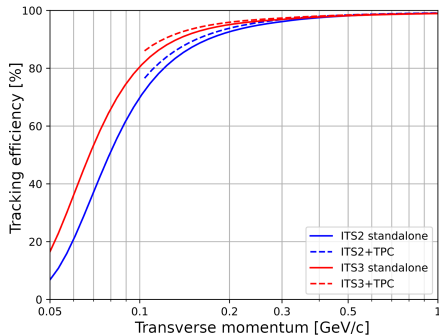
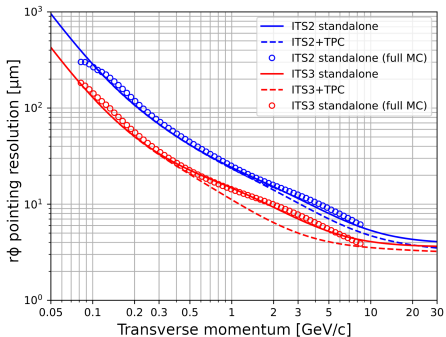


Beam pipe Inner/Outer Radius (mm)	16.0/16.5		
IB Layer Parameters	Layer 0	Layer 1	Layer 2
Radial position (mm)	18.0	24.0	30.0
Length (sensitive area) (mm)	280		
Pseudo-rapidity coverage	$\pm 2.5$	$\pm 2.3$	$\pm 2.0$
Active area (cm <sup>2</sup> )	610	816	1016
Pixel sensor dimensions (mm <sup>2</sup> )	280 x 56.5	280 x 75.5	280 x 94
Number of sensors per layer	2		
Pixel size ( $\mu\text{m}^2$ )	0 (10 x 10)		

- Key ingredients:
  - ▶ 280 mm wafer-scale sensors, fabricated using **stitching** (Tower Partners Semiconductor (TPSCo) 65 nm CMOS Imaging Sensor (CIS) process)
  - ▶ Thinned down to 20-40  $\mu\text{m}$  (0.02-0.04%  $X_0$ ), making them **flexible**
  - ▶ Bent to the target radii
  - ▶ Mechanically held in place by **carbon foam ribs**
- Key benefits:
  - ▶ Extremely low material budget: 0.02-0.04%  $X_0$  (beampipe: 500  $\mu\text{m}$  Be: 0.14%  $X_0$ )
  - ▶ Homogeneous material distribution: negligible systematic error from material distribution

**THE WHOLE DETECTOR WILL COMPRISE SIX (!) SENSORS (CURRENT ITS IB: 432) AND BARELY ANYTHING ELSE**

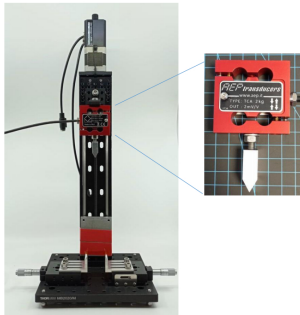
# ITS3 performance



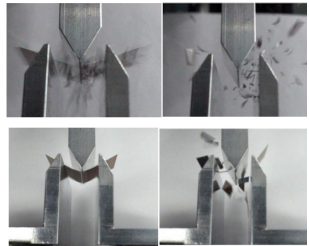
- Improvement on pointing resolution is **factor of 2** over all momenta.
- Large improvement on tracking efficiency especially for low momenta.



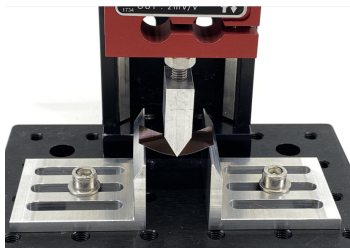
# Bending Test



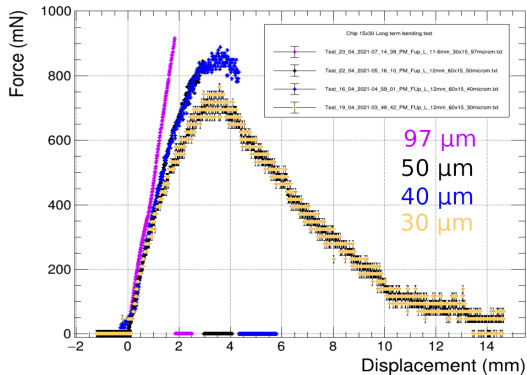
- Bending modulus
- Elastic - plastic region
- Breaking point
- Minimum radius



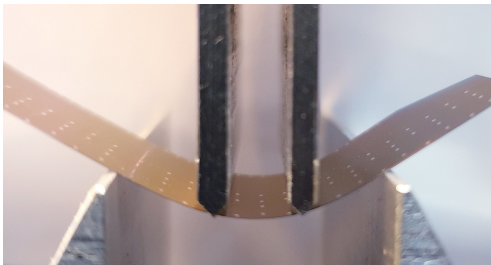
# Bending Test (3-point test)



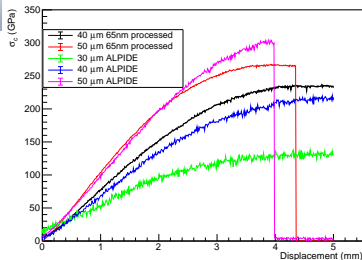
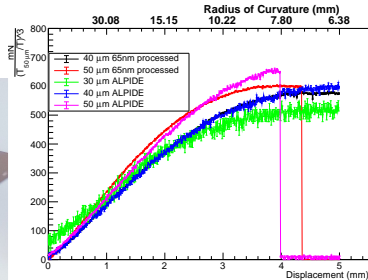
## ALICE ITS3 Bending test



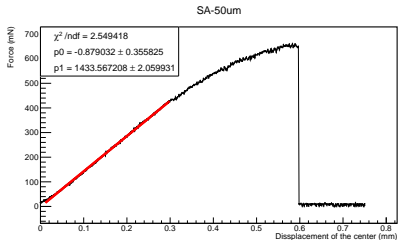
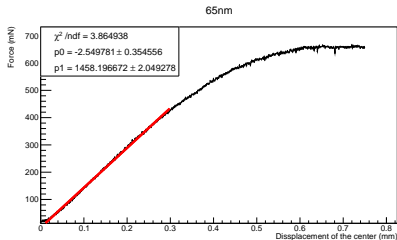
# Bending Test (4-point test)



- 4-point test helps to have a more uniform curvature
- ..



# Bending Test (4-point test)



Sensor	Young's Modulus (GPa)
65nm-40um	$104 \pm 63$
65nm-50um	$126 \pm 76$
SuperALPIDE-30um	$89 \pm 54$
SuperALPIDE-40um	$102 \pm 62$
SuperALPIDE-50um	$117 \pm 71$
Single Crystal Silicon	130-185

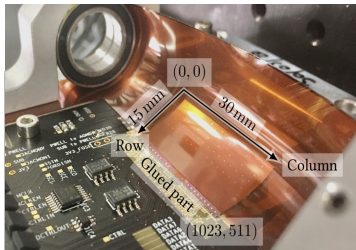
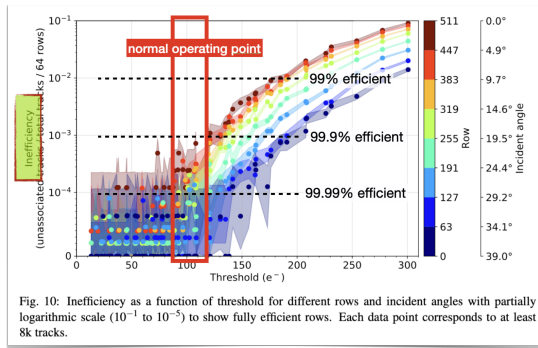
# Bending Tests

- Monolithic Active Pixel Sensors are quite flexible
  - ▶ already at thicknesses that are used for current detectors
- Bending force scales as (thickness)<sup>-3</sup>
  - ▶ large benefit from thinner sensors
- Breakage at smaller radii for thinner chips
  - ▶ again benefit from thinner sensors

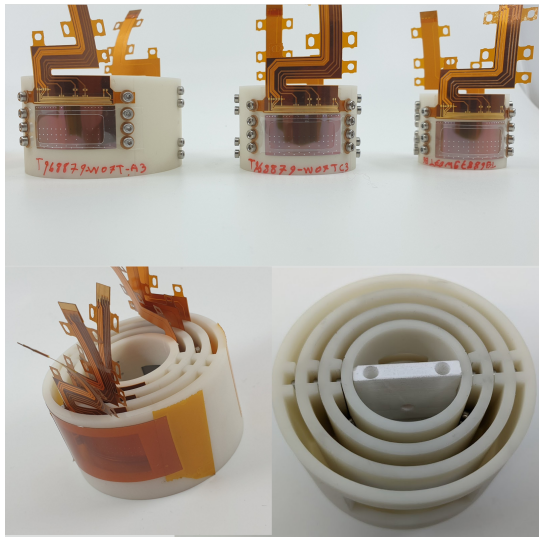
ITS3 TARGET RADIUS AND THICKNESS ARE VERY FEASIBLE

# Bent ALPIDE

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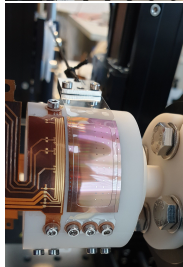
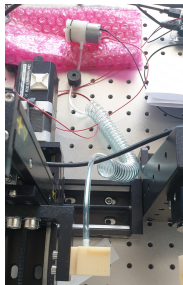
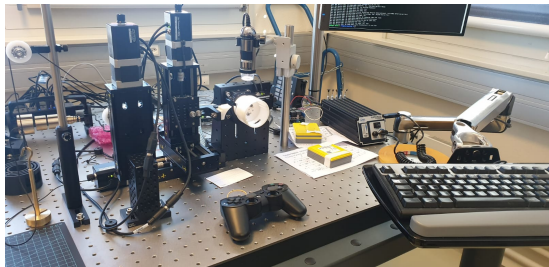


- Bent ALPIDE has **high efficiency**
- ASICs are functional in bent ALPIDE



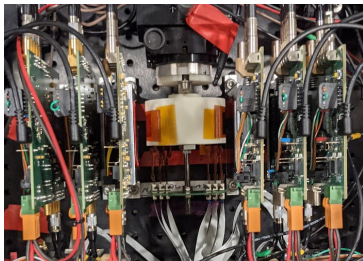
- $\mu$ ITS3 a mock-up of final ITS3
  - ▶ 6 ALPIDE bent to **ITS3 target radii**
  - ▶ Experience with handling thin, bent silicon was gained
- A Cu target is placed in the center, expect to see 120 GeV **p-Cu collisions**

# $\mu$ ITS3 Preparation Setup

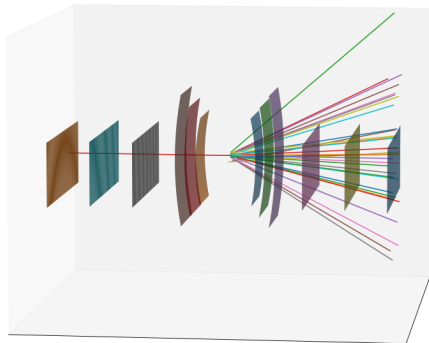
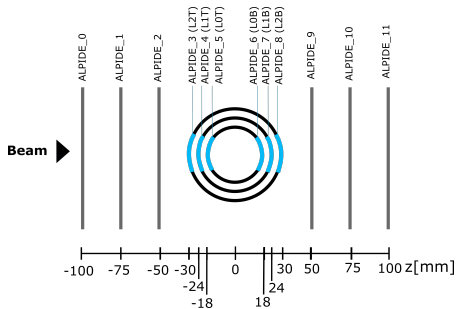




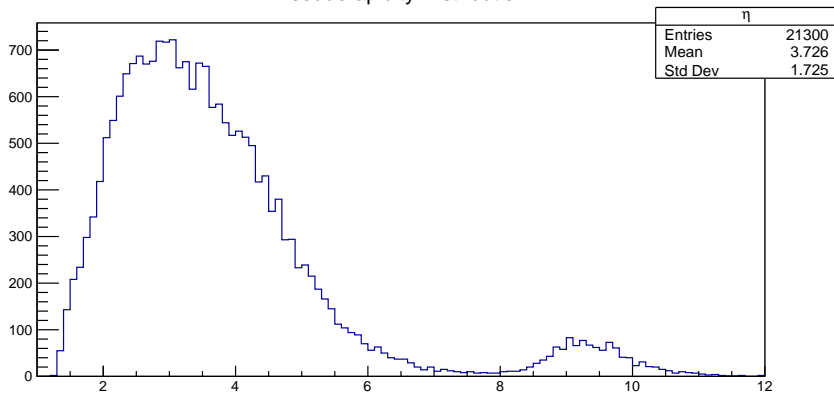
# $\mu$ ITS3 in Testbeam

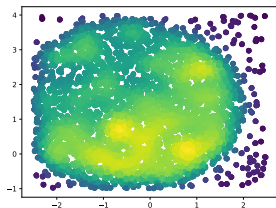


- The setup has tested in SPS
- 120 GeV hadron beam is used.

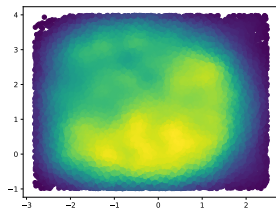


Pseudorapidity Distribution

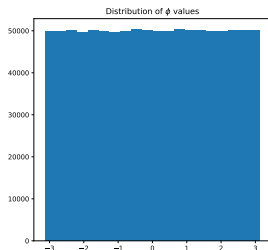
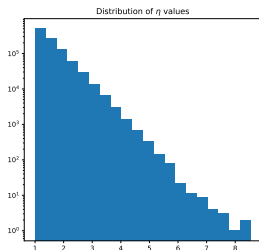




Vertex positions of real Data



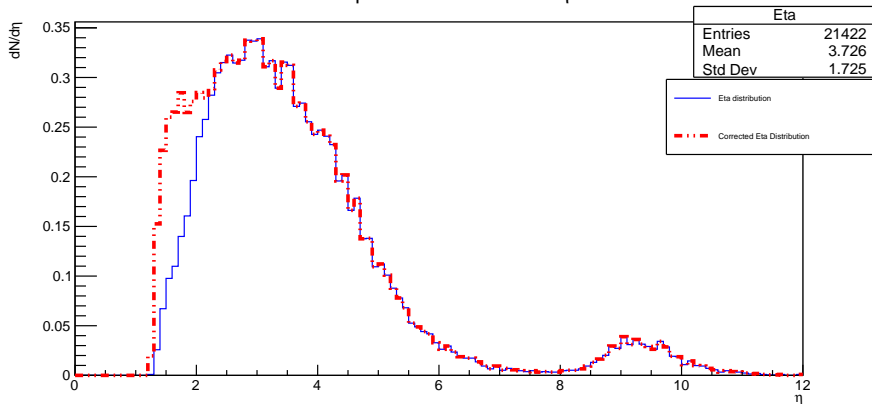
Generated vertex positions



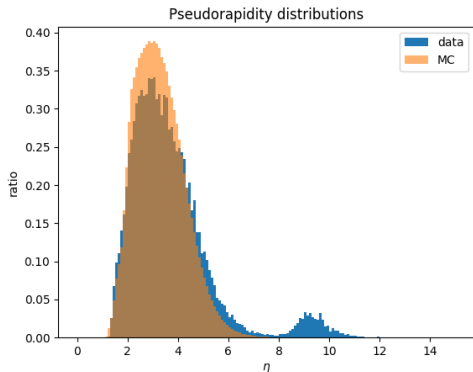
Generated tracks

- $10^6$  Random tracks are created to check geometrical acceptance of the detector

## Acceptance Correction on $\eta$

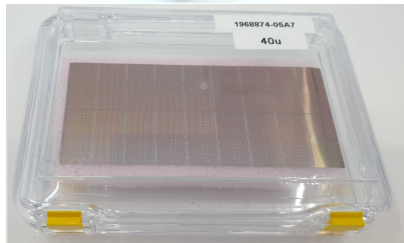
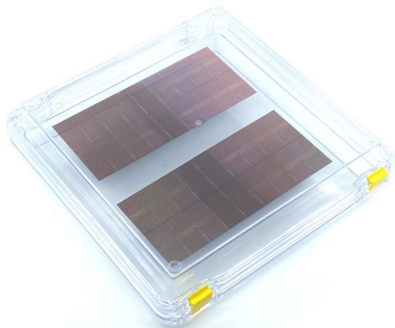


# $\mu$ ITS3 comparison with pythia



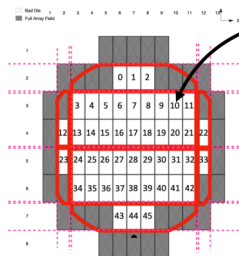
Pythia version	8.310
Number of events	99869
Collision Type	Fixed Target
Beam Energy	120 GeV
Beam particle	$\pi^+$
Target	Cu

# Super ALPIDE

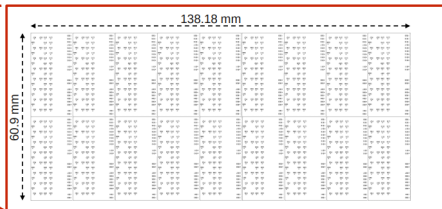


- To study the **bending** and **interconnection** of large pieces of processed chips, "super-ALPIDE" is built.
- Comprises of **1 silicon piece cut** from an ALPIDE wafer size of  $14\text{ cm} \times 6\text{ cm}$

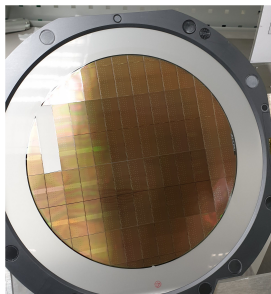
# Super ALPIDE



ALPIDE chips

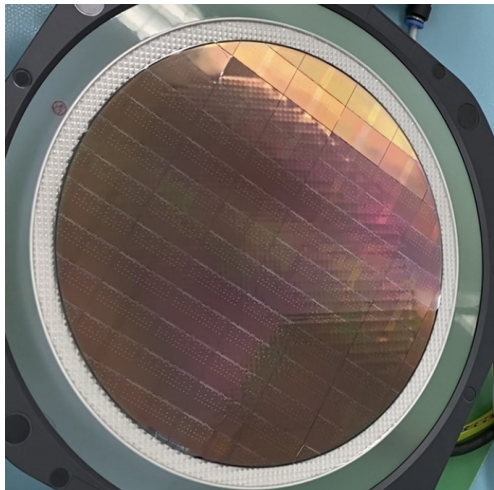


18 ALPIDE chips, covering about a half of an ITS3 half-Layer0



- Super-ALPIDEs are actually an array of ALPIDEs.
- They consist  $9 \times 2$  ALPIDE chips.

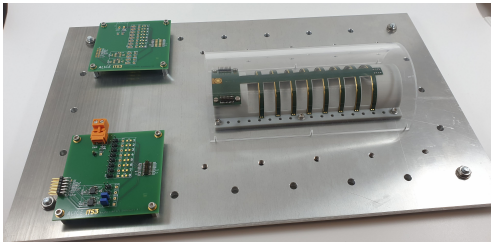
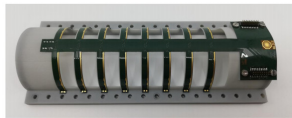
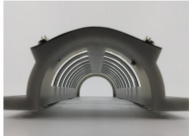
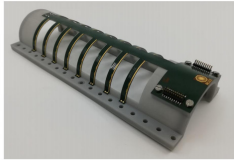
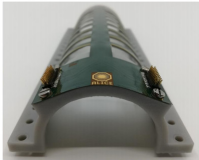
# Picking up Super ALPIDE Chips



- Tested different methods how to pick large and very thinned chips
- Die-ejector with fine grid is the most efficient.

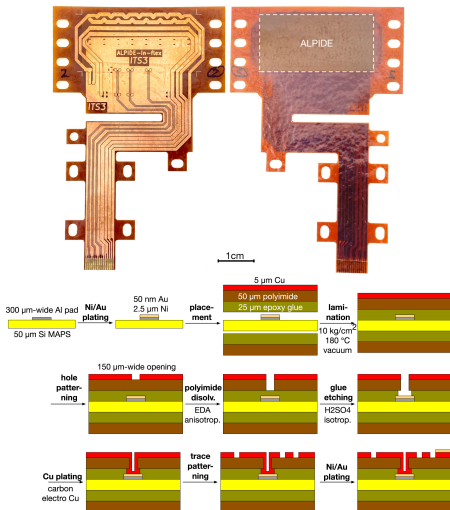


# Exoskeleton



- 3-D printed.
- Designed to support super-ALPIDEs after bending.
- Windows to reach interconnection points at middle of super-ALPIDE

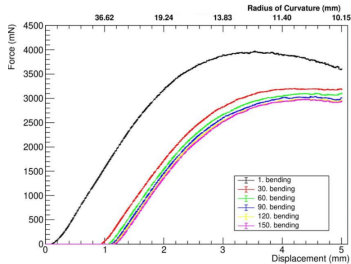
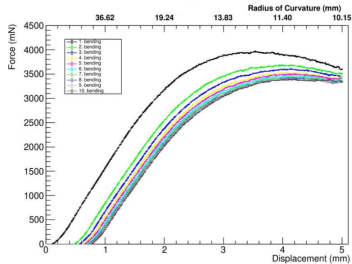
# MAPS in Foil



- A method to protect MAPS and its interconnection as part of R&D for bending thin silicon.
- MAPS are embedded in polyimide film with a copper layer for interconnections.
- For the first prototype ALPIDE sensors are used.
- Features:
  - ▶ Mechanical support
  - ▶ Mechanical protection
  - ▶ Electrical interconnection

[doi.org/10.1016/j.nima.2021.166280](https://doi.org/10.1016/j.nima.2021.166280)

# MAPS in Foil



- Mechanical and bending tests indicates polyimide film successfully protects sensors from mechanical damages
- Unlike naked MAPS, bending process is not totally irreversible

- Silicon is **flexible** enough to achieve targeted radii for ITS3
- The efficiency of bent MAPS is close enough to flat ones
- Thanks to **Super-ALPIDE** study we have the know-how about how to deal with large and thin chips
- Further R&D for assembly and operation for bent MAPS are ongoing